

November 2, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
U.S.A.

Re: Correction of International Application Number in an
Existing Utility Patent Application

Application No.: 10/598,933

Confirmation No.: 2213

Filing date:

Believed to be September 14, 2006

Title:

SEMICONDUCTOR WAFER INSPECTION

DEVICE AND METHOD

Application Type:

U.S. National Stage under 35 USC 371

Atty. Docket No:

PA214WP002

First Inventor:

Fumi NABESHIMA

Assignee:

Komatsu Electronic Metals Co., Ltd.

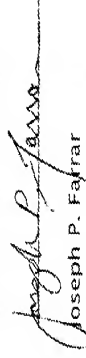
Sir:

With regard to the captioned patent application: An error is noted in the International Application Number therefor.

The correct International Application Number is PCT/JP05/07120.

It is respectfully requested that the Office update its records to reflect the correct International Application Number provided herein.

Respectfully submitted,



Joseph P. Farrar
Attorney Registration No. 54, 596
Kanda Center Building 5th Floor
3-2, Kajicho 2-chome
Chiyoda-ku, Tokyo 101-0044 Japan
Tel/Fax: 011-81-3-6804-7145
Email: orionjpf@dune.ocn.ne.jp

JF/so